

Vacuum ▶ PVD Thin films ▶ Leak testing ▶ Plasma



# High throughput Electron beam evaporator

**EVA760**



*by*

**allianceconcept**

## High productivity and low up time, the machine EVA760 is a partner for your success

Thanks to its volume, the EVA760 system can be set up using a **wide range of complex configurations**.

This configurable equipment as well as all the others products of the range, can handle a large number of substrates per run.

Its generously sized pumping system ensures a high throughput.

Combined optical and mechanical (quartz) thickness measurement, ion assisted deposition (IAD), co-evaporation, partial pressures regulation through RGA, glow discharge... are all features that can be integrated into your system.



### Main features

<b>Vacuum chamber diameter :</b>	760 mm
<b>Height :</b>	920 mm
<b>Volume :</b>	520 litres
<b>Ultimate vacuum (cryogenic configuration) :</b>	$5.10^{-8}$ mbar <sup>[1]</sup>
<b>System throughput :</b>	10 x 6"
<b>Planar configuration uniformity :</b>	< +/- 5% <sup>[1]</sup>
<b>Through the wall installation :</b>	Yes
<b>Fully automatic system controller :</b>	- Process management - Traceability

<sup>[1]</sup> These values have been measured on equipment we have delivered and should be handled as information only. The features of a system depend on its final configuration.

